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To: Commissioner for Patents
Art Unit 2812

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From: Ira Matsil

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Applicant: Chen, *et al.*

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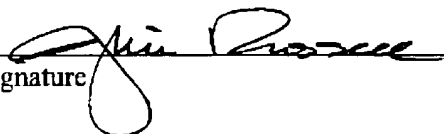
For: Direct, Non-Destructive Measurement of Recess Depth in a Wafer

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